

# Resolving chemical states of p-GaN:Cs photocathodes with *in-situ* X-ray photoelectron spectroscopy (XPS)

## Introduction

- New photocathodes with higher QE are desired for particle accelerator injectors (to provide higher beam currents)
- p-type GaN is able to produce a negative electron affinity (NEA) when cesium is deposited on the surface
- A thermal cleaning under vacuum was carried out to achieve an atomically clean surface

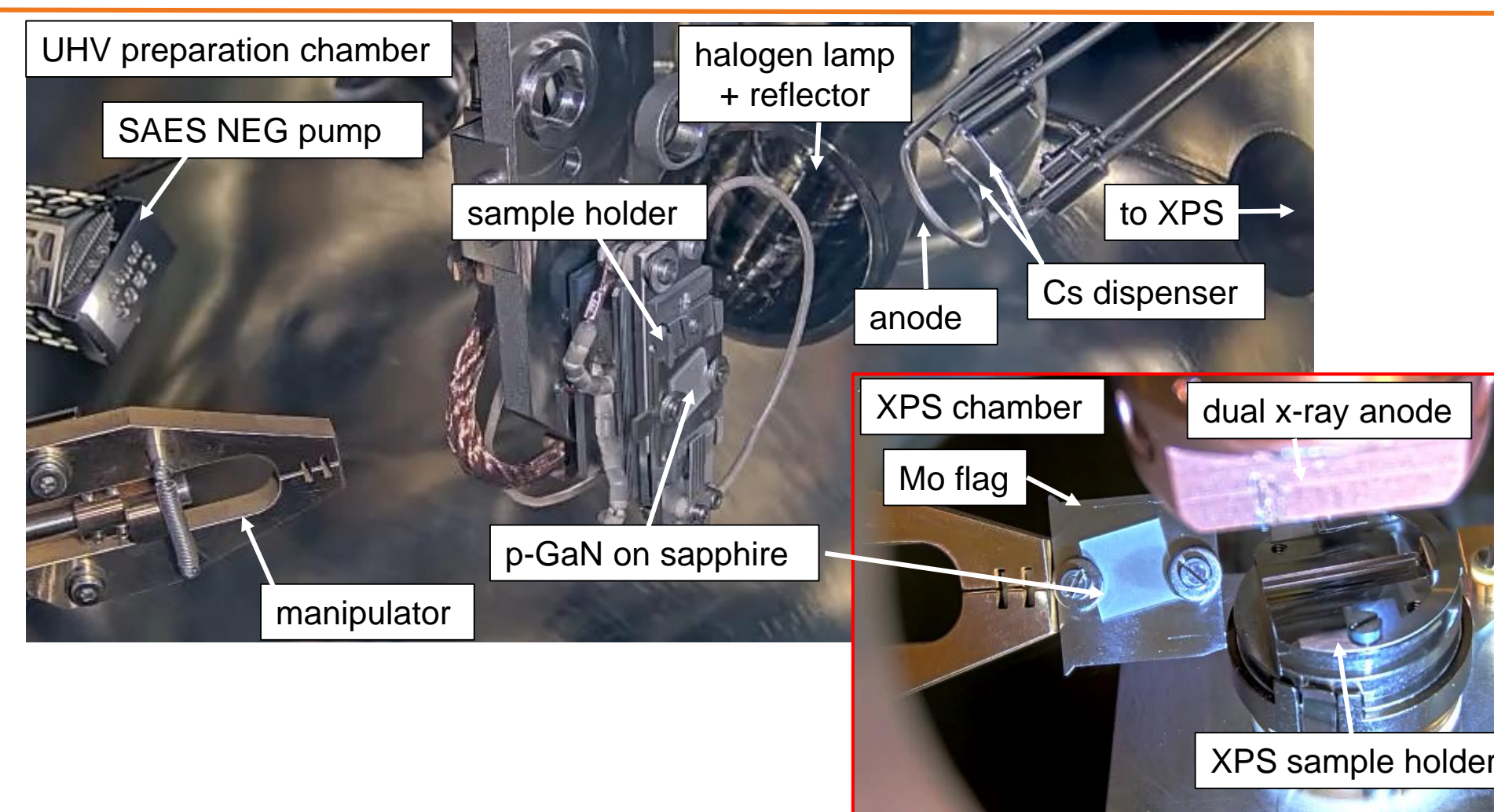


Fig. 1: The interior of the UHV preparation chamber (showing a sample holder, a halogen lamp, an anode, and cesium dispensers) and the XPS analysis chamber connected to the preparation chamber.

## Methods and Material

- The p-GaN surface is studied with *in-situ* XPS without leaving UHV environment
- A PHI 5600 spectrometer (average pressure of  $4 \times 10^{-9}$  Torr and Al K $\alpha$  line ( $h\nu = 1486.6$  eV) from non-monochromatized x-ray source was used
- p-GaN (5  $\mu\text{m}$ ), grown on sapphire with metalorganic chemical vapor deposition (MOCVD); Mg conc.:  $5 \times 10^{16} - 1 \times 10^{17} \text{ cm}^{-3}$

## Results

### 1) Thermal cleaning of p-GaN surface

- p-GaN was rinsed in 99 % pure EtOH
- EtOH solvent residues (C-OH) remained on the p-GaN surface
- After thermal cleaning: peak intensity of EtOH residuals was reduced

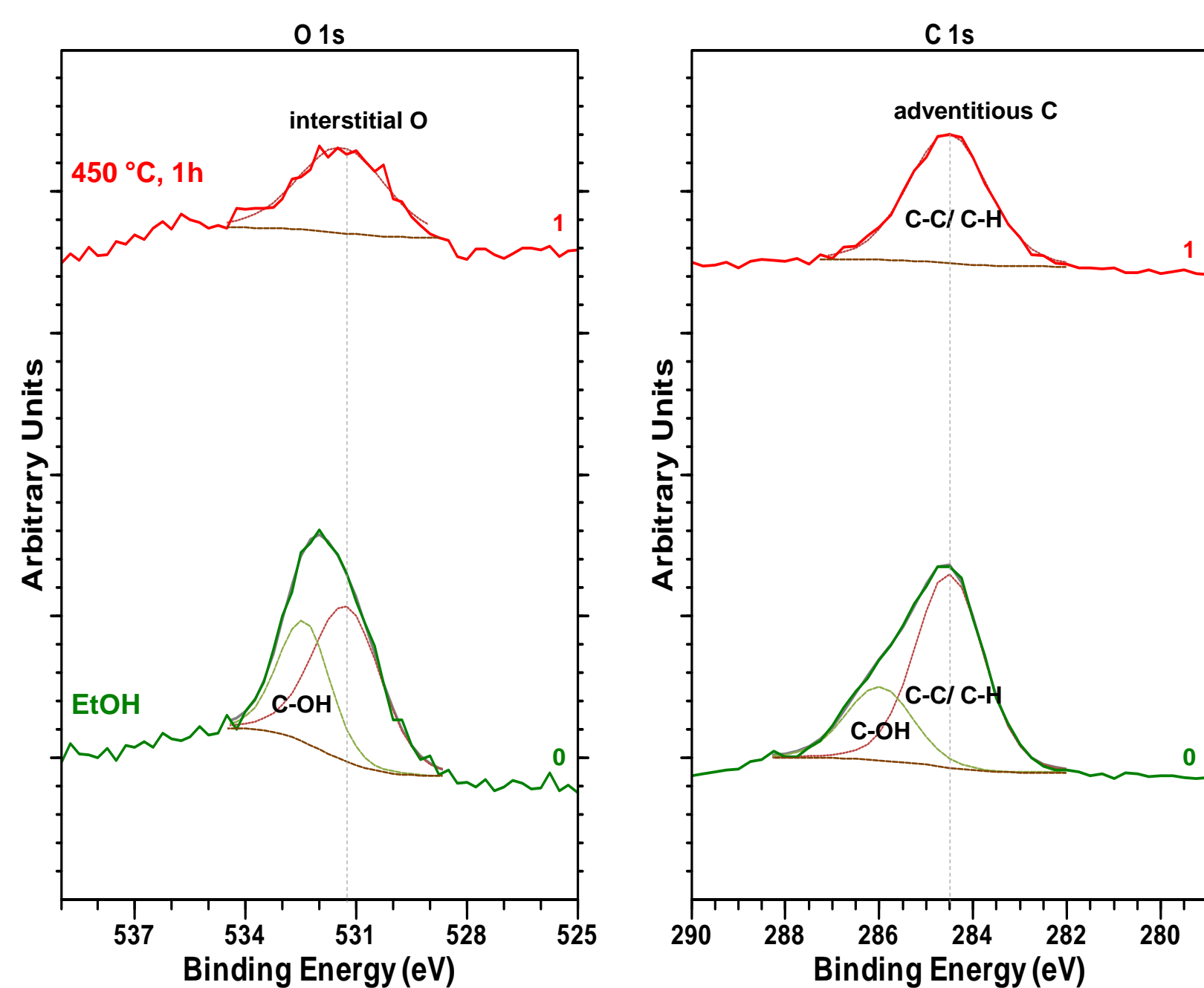


Figure 2: O 1s and C 1s photoelectron spectra for the p-GaN surface cleaned with 99 % EtOH (line 0) and after thermal cleaning (line 1).

- Thermal cleaning was not able to remove O and C entirely
- C and O contaminants remained
- Derive from MOCVD ?

### 2) p-GaN:Cs photocathode

- Cs was deposited on the p-GaN to achieve a NEA surface (photocathode)
- Cs current: 3.0 – 4.0 A ( $3 \times 10^{-9}$  mbar)
- p-GaN was illuminated with 310 nm UV-LED during the Cs deposition
- *In-situ* photocurrent was observed until a maximum was achieved

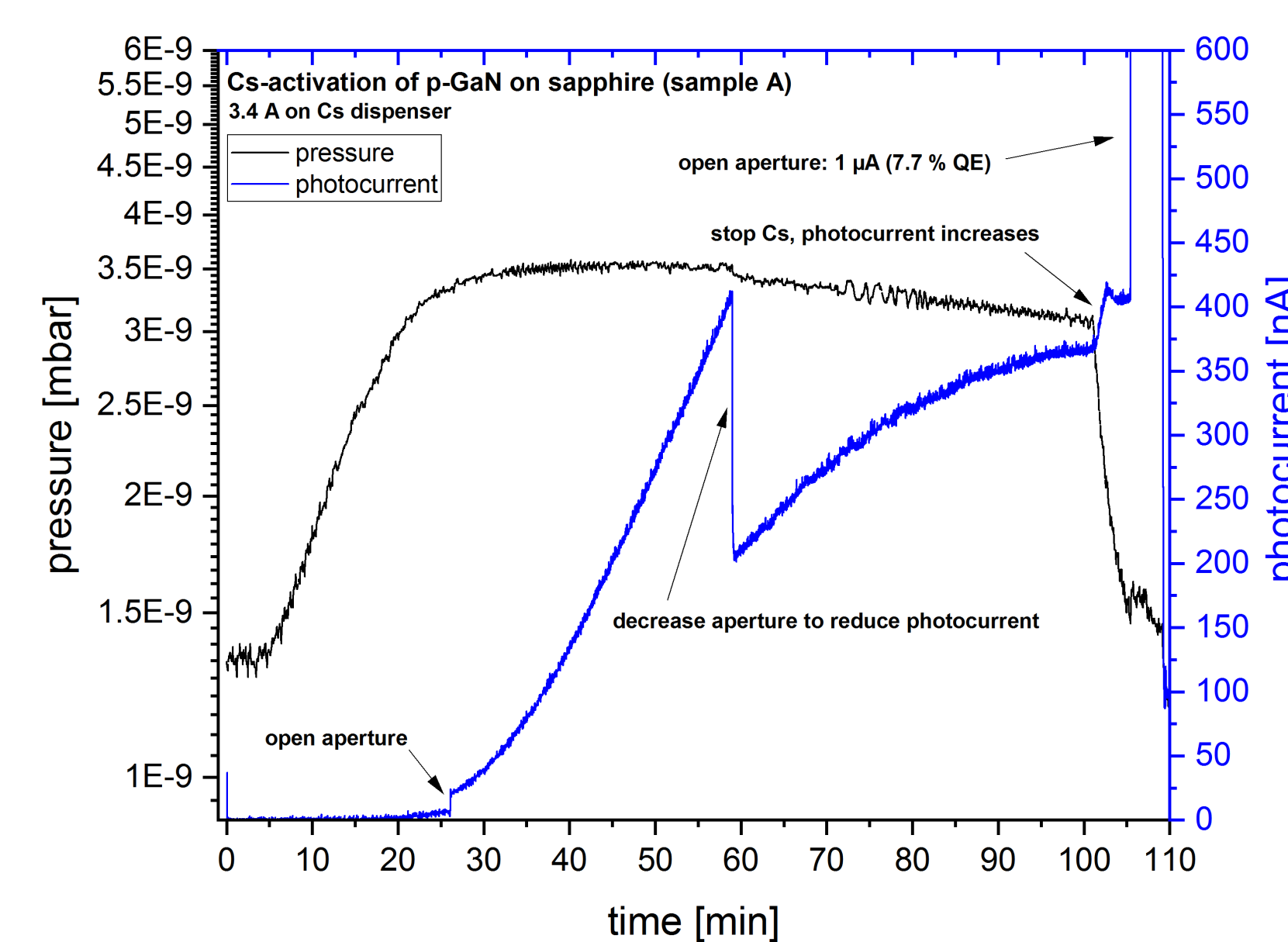


Figure 3: *In-situ* photocurrent and vacuum value during the cesium activation of the p-GaN surface.

$$QE = \frac{h \cdot c}{q_e \cdot \lambda \cdot P_{\text{Light}}}$$

- 7.7 % QE was achieved although C and O remained on the surface

### 3) Surface after Cs deposition (XPS)

- Cs caused a shift toward higher BE in Ga 3d<sub>3/2</sub> and N 1s, but not in O 1s
- Peak intensities were normalized in their background
- N 1s had an overlap with Ga LMM Auger by Al excitation
- C remained at a BE of 284.6 eV

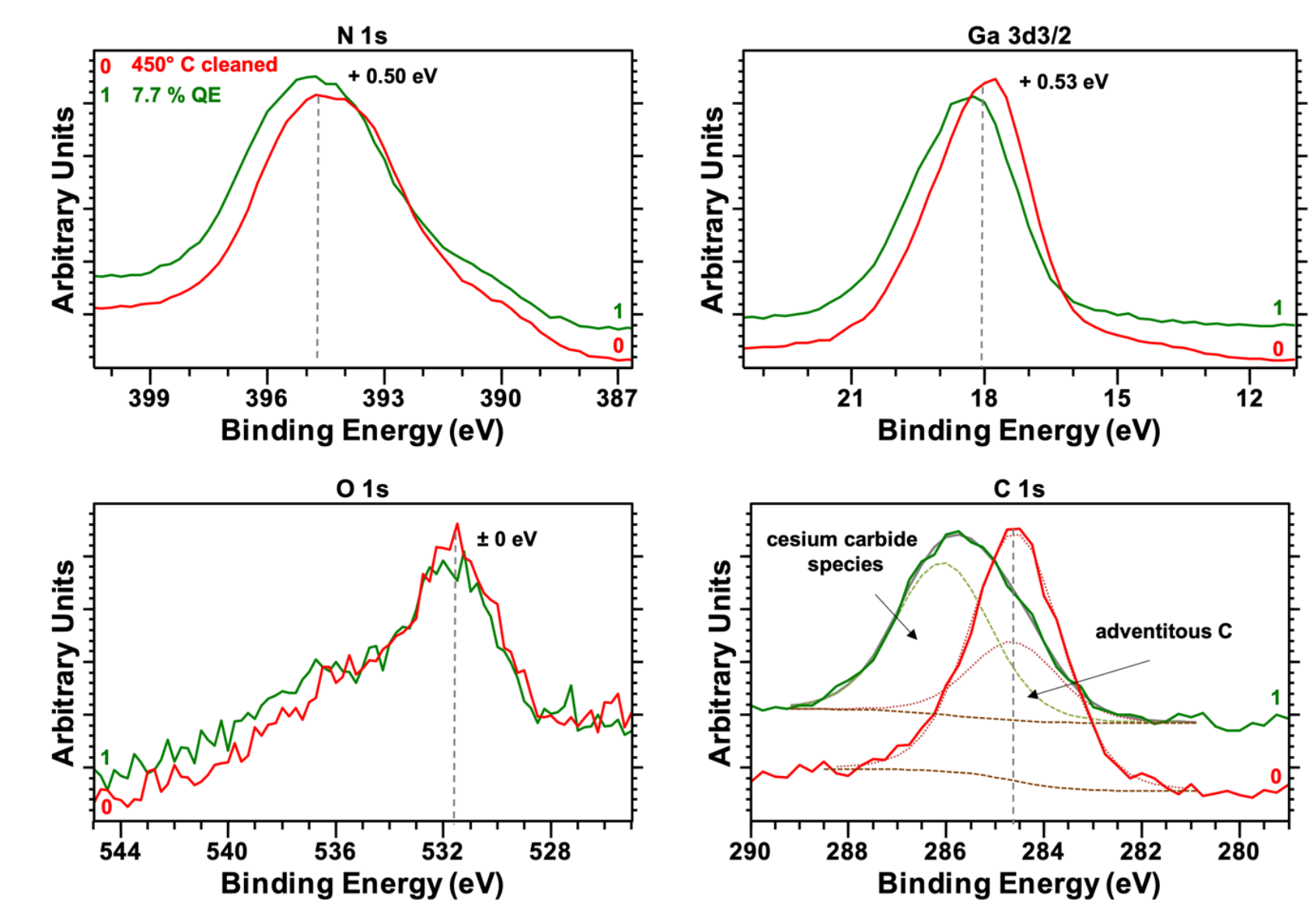


Figure 4: Ga 3d<sub>3/2</sub>, N 1s, O 1s, and C 1s photoelectron spectra for the p-GaN surface after thermal cleaning (line 0) and after Cs activation with 7.7 % QE (line 1).

- most influence was observed in C 1s peak: new component appeared at 286 eV
- → cesium carbide species

### 4) Photocathode degradation

- QE decays 1/e, but X-ray accelerated the natural degradation
- Photoemission peaks shifted toward lower BE during degradation

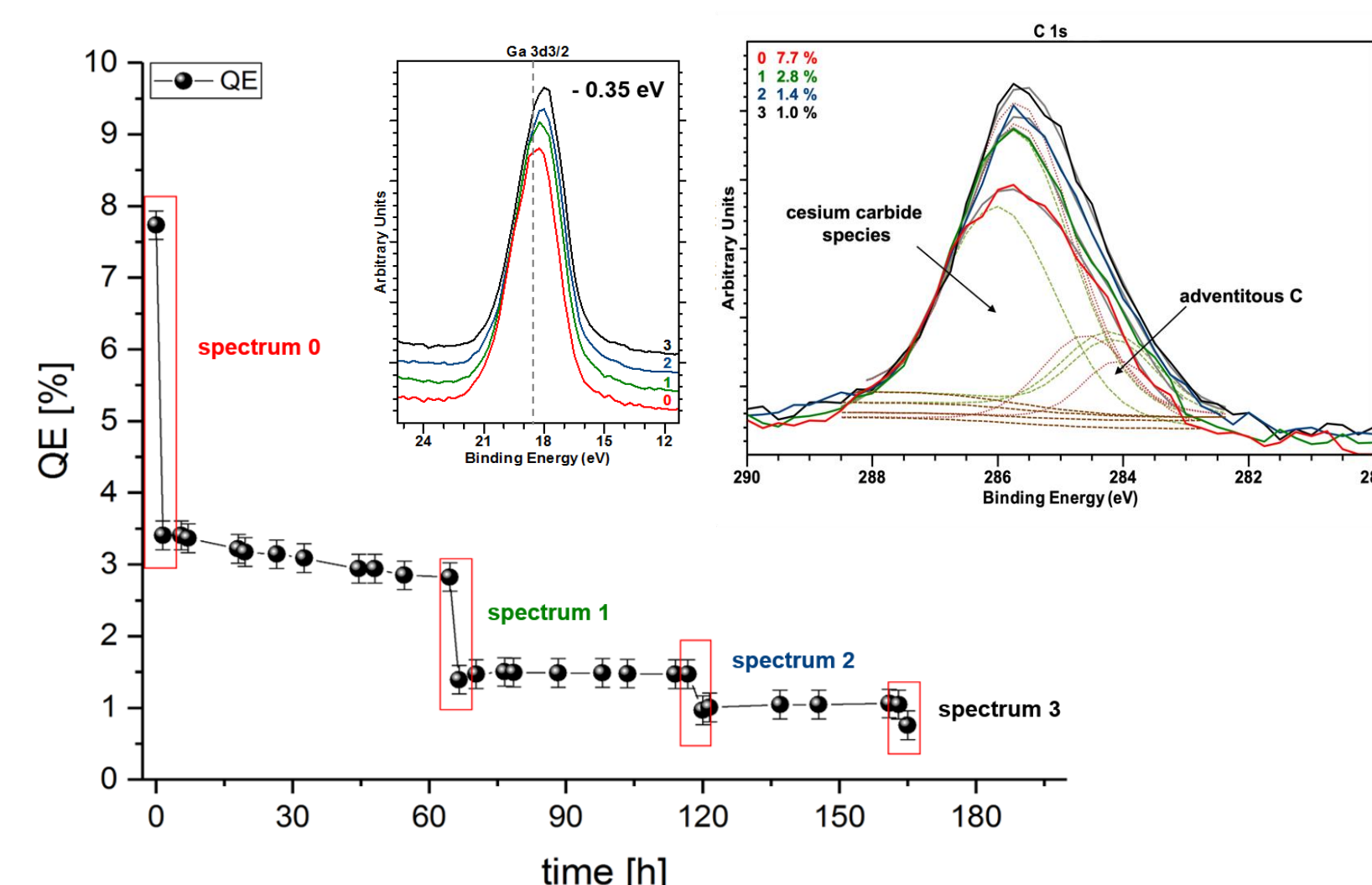


Figure 5: The QE decay of the p-GaN:Cs photocathode and the Ga 3d<sub>3/2</sub> and C 1s photoemission spectra at different times during its decay. The C 1s spectrum showing the evolution of the cesium carbide species.

- C 1s showed a different behavior:
- peak intensity for cesium carbide species (286 eV) increased with ongoing degradation

### 5) Achieved QE values for p-GaN:Cs photocathodes on sapphire

- QE depended strongly on the applied temperature used in the thermal cleaning
- QE was influenced by the surface conditions

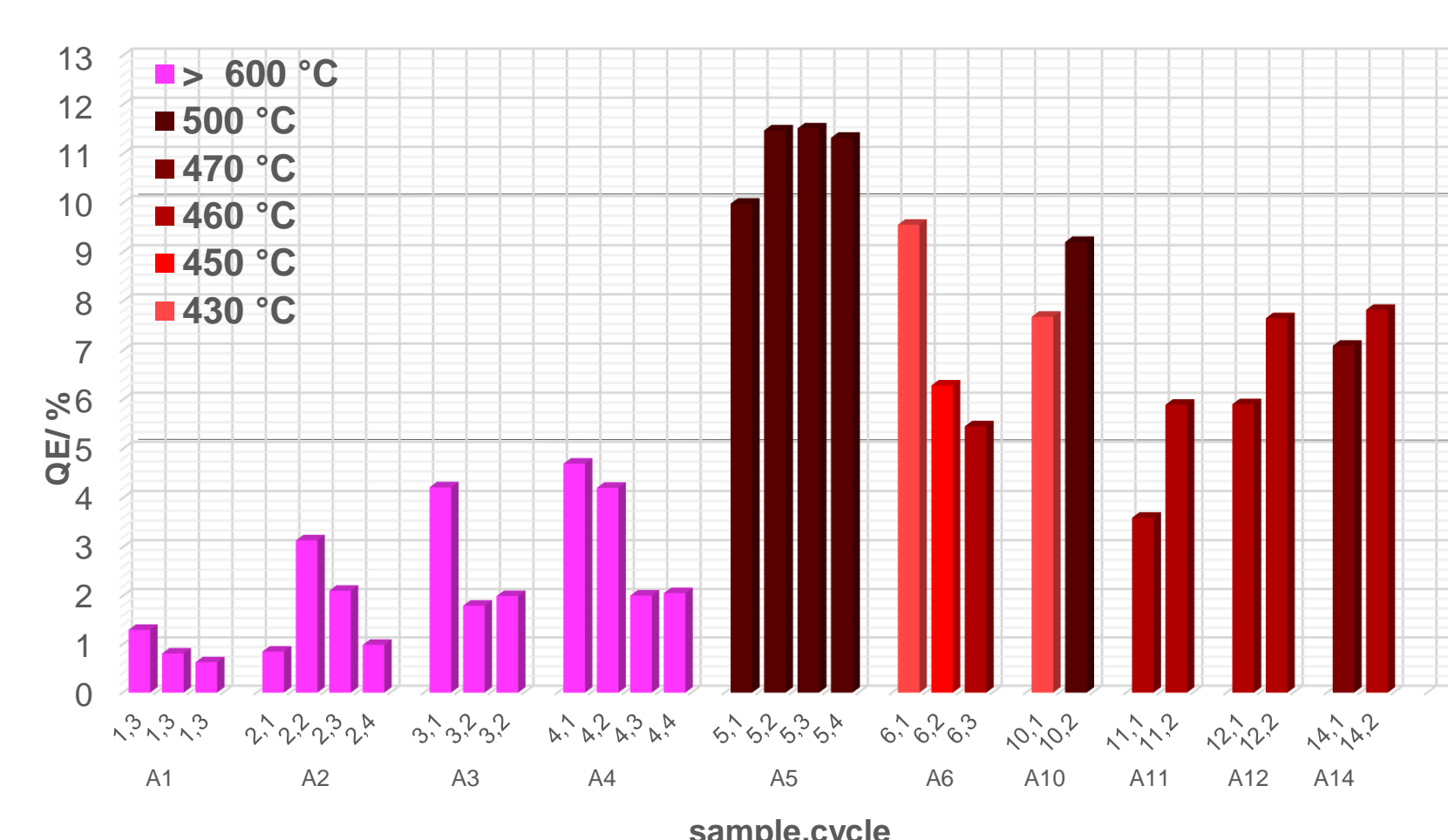


Figure 6: Achieved QE values of the p-GaN:Cs photocathodes depending on their surface conditions (applied T in thermal cleaning).

- High QE (max. 11.5 %) were achieved @ moderate temperature (400–500 °C)
- Less QE @ T > 600 °C

## Conclusion

- p-GaN shows an enormous potential to be a new photocathode for particle accelerators
- Thermal cleaning cannot remove O and C contaminations entirely
- C and O were residuals from MOCVD ?
- Cs caused a shift toward higher BE
- But C 1s showed different behavior: new species was created
- Formation of cesium carbide species caused an external degradation +
- X-rays accelerated the photocathode degradation

## Outlook

- p-GaN with higher quality (MBE or HVPE)
- On different substrates ? (SiC, Si)
- Remove C and O with ion sputtering ?
- Influence of Mg concentration on QE ?